

Substitute for form 1449A/PTO			Complete, if Known	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)			Application Number	<del>New York Assigned</del> 10/719858
			Filing Date	Herewith 11-20-03
			First Named Inventor	Mäler, David
			Art Unit	<del>New York Assigned</del> 2834
			Examiner Name	<del>New York Assigned</del> T. Dougherty
Sheet 1	of 3	Attorney Docket Number	019930-002830	

U.S. PATENT DOCUMENTS*					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number Number Kind Code <sup>2</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
TMD	AA	5,414,540	05/09/95	Patel et al.	359 39
TMD	AB	5,917,625	06/29/99	Ogusu et al.	359 130
TMD	AC	5,999,672	12/07/99	Hunter et al.	385 37
TMD	AD	6,028,689	02/22/00	Michalick et al.	359 224
TMD	AE	6,040,935	03/21/00	Michalick	359 198
TMD	AF	6,097,859	08/01/00	Solgaard	385 17
TMD	AG	6,108,471	08/22/00	Zhang et al.	385 37
TMD	AH	6,128,122	10/03/00	Drake et al.	359 224
TMD	AI	09/442,061	11/16/99	Weverka, et al.	
	AJ	US-			
	AK	US-			
	AL	US-			
	AM	US-			
	AN	US-			
	AO	US-			
	AP	US-			
	AQ	US-			
	AR	US-			
	AS	US-			
	AT	US-			

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T*
		Country Code <sup>2</sup>	Number <sup>3</sup>	Kind Code <sup>4</sup> (if known)				
	AU							<input type="checkbox"/>
	AV							<input type="checkbox"/>
	AW							<input type="checkbox"/>
	AX							<input type="checkbox"/>
	AY							<input type="checkbox"/>
	AZ							<input type="checkbox"/>
	BA							<input type="checkbox"/>
	BB							<input type="checkbox"/>

Examiner Signature	Thomas M. Dougherty	Date Considered	12/1/03 and 10/29/04
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 Kind Codes of U.S. Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 601.04. \*Enter Office that issued the document, by the two-letter code (WIPO Standard ST-3). \*For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. \*Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST-16 if possible. \*Applicant is to place a check mark here if English language Translation is attached.  
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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 2

of

3

**Complete If Known**

Application Number	Not Yet Assigned 10/714858
Filing Date	Herewith 11-22-03
First Named Inventor	Miller, David
Art Unit	Not Yet Assigned 2634
Examiner Name	Not Yet Assigned T. O'NEILL
Attorney Docket Number	019930-002830

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS); title of the article (when appropriate); title of the item (book, magazine, journal, serial, symposium, catalog, etc.); date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
TMO	BC	T. Akiyama, et al., "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993, pp.106-110	
TMO	BD	Kenneth Bean, et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978	
TMO	BE	Dino R. Ciarlo, "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992	
TMO	BF	A.S. Dewa, et al., "Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96	
TMO	BG	Joseph Ford et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
TMO	BH	J. Grade et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
TMO	BI	V. Kaajakari et al., "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SPIE Vol. 4180 (2000); pp. 60-65	
TMO	BJ	T.L. Koch et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987	
TMO	BK	I. Nishi et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 <sup>th</sup> May 1985	
TMO	BL	P. Philippe et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
TMO	BM	M. Schilling et al., "Deformation-free overgrowth of reactive ion beam etched submicron structures in InP by liquid phase epitaxy," Appl. Phys. Lett. 49 (12), 22 September 1986	
TMO	BN	Z. J. Sun et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998	
TMO	BO	W. Tang, et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990; pp. 198-202	
TMO	BP	L. Torcheux et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem Soc., Vol. 142, No. 6, June 1995	

Examiner  
Signature

Rhonda M. Dougherty

Date  
Considered

2/10/03 and 10/24/04

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Substitute for form 1449B/PTO		<b>Complete if Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		Application Number	Non-Math Assigned <b>N/119658</b>
		Filing Date	Herewith <b>11-20-03</b>
		First Named Inventor	Miller, David
		Art Unit	Non-Math Assigned <b>2634</b>
		Examiner Name	Non-Math Assigned <b>T. Dougherty</b>
Sheet <b>3</b>	of <b>3</b>	Attorney Docket Number	019930-002830

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS); title of the article (when appropriate); title of the item (book, magazine, journal, serial, symposium, catalog, etc.); date; page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
<b>TMD</b>		P. VanKessel et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
<b>TMD</b>		Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; dissertation by C. Keller, Fall 1998	
<b>TMD</b>		Gimballed Electrostatic Microactuators with Embedded Interconnects; dissertation by L. Muller; Spring 2000	

Examiner Signature	<b>Blawie M. Dougherty</b>	Date Considered	<b>12/1/03 and 10/29/04</b>
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<sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> Applicant to place a check mark here if English language Translation is attached.